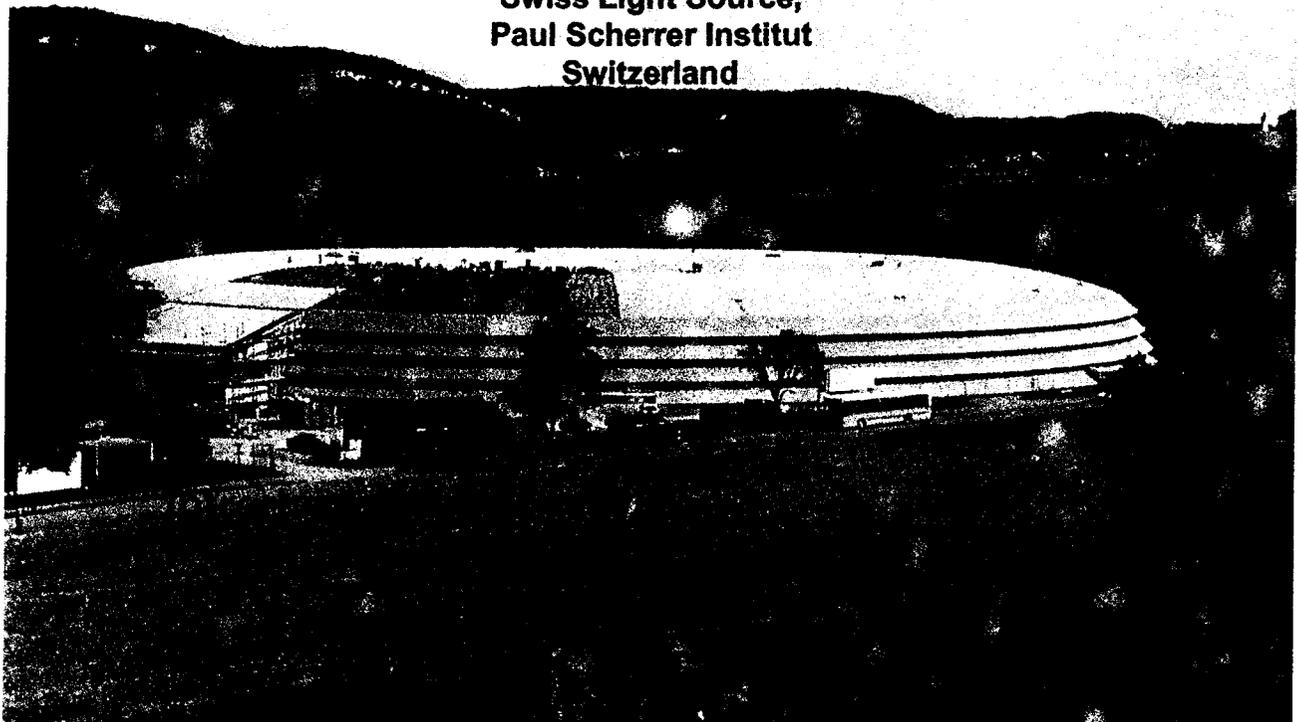


Workshop on Detectors for Synchrotron Research
30-31, 2000, in Washington, DC

Pixel and Microstrip Detectors for Synchrotron Radiation Applications: Digital Systems

Ch. Brönnimann,
Swiss Light Source,
Paul Scherrer Institut
Switzerland



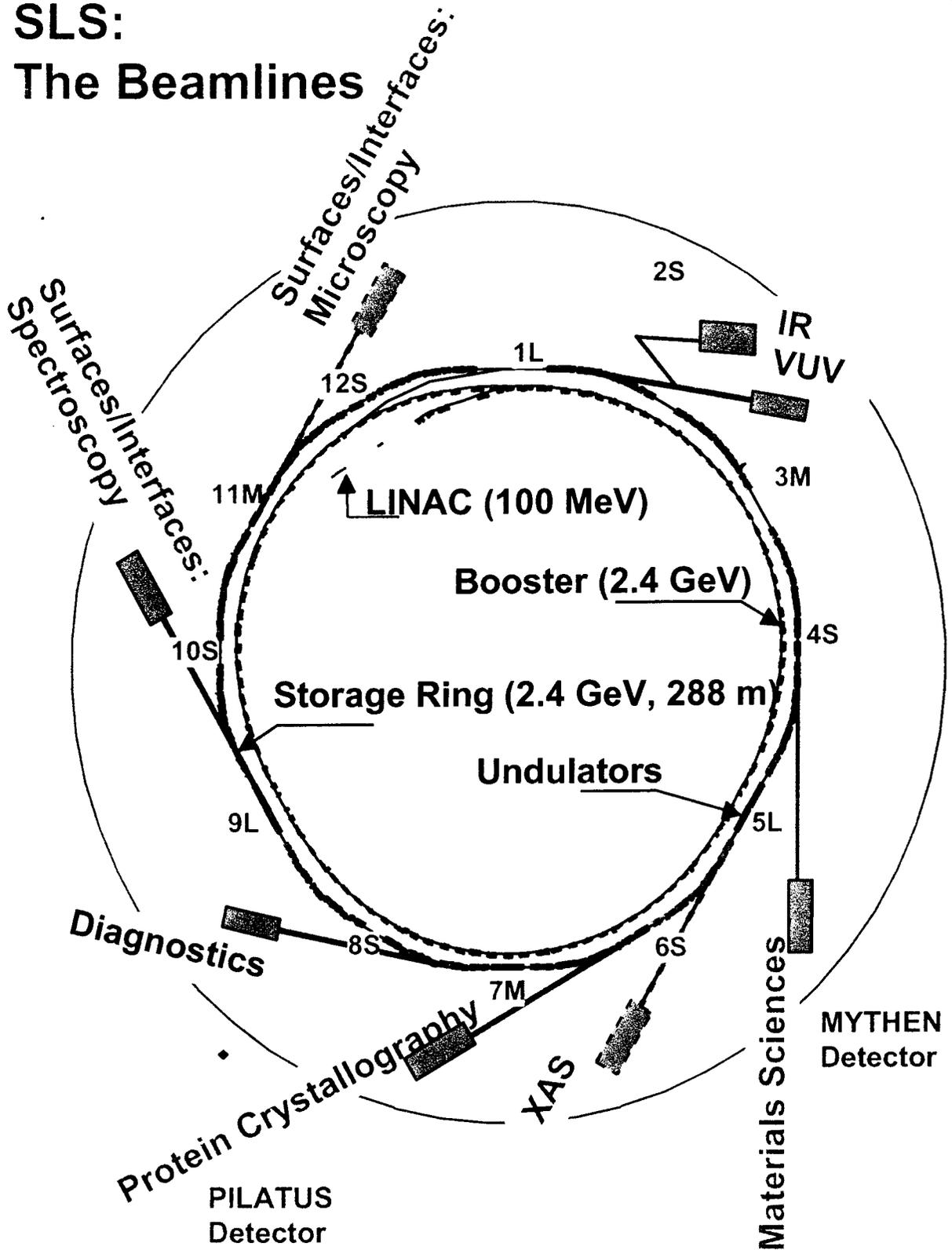
Summary and Conclusions

Ch. Brönnimann¹, E. Eikenberry¹, B. Schmitt¹, R. Baur² and R. Horisberger²
Ch. Bühler², U. Greuter², M. Näf¹, S. Streuli², R. Brun¹

¹ Swiss Light Source, Paul Scherrer Institut, CH-5232 Villigen-PSI

² Paul Scherrer Institut, CH-5232 Villigen-PSI

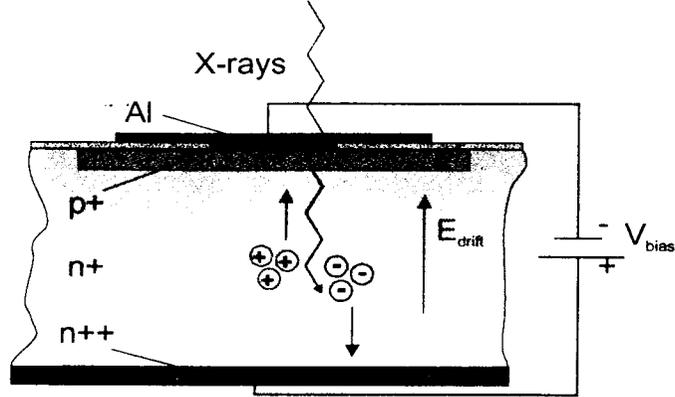
SLS: The Beamlines



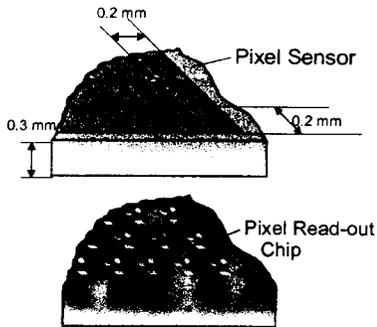
Pixel and Microstrip Detectors

Si pn-junction

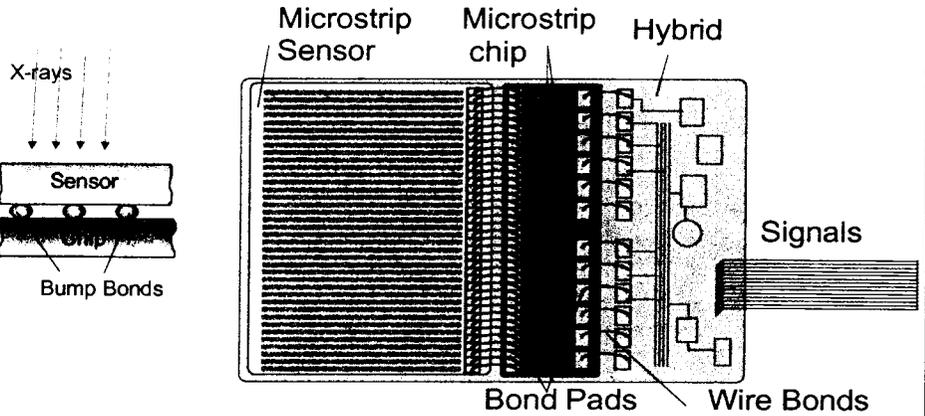
3.6 eV to create
1 eh-pair



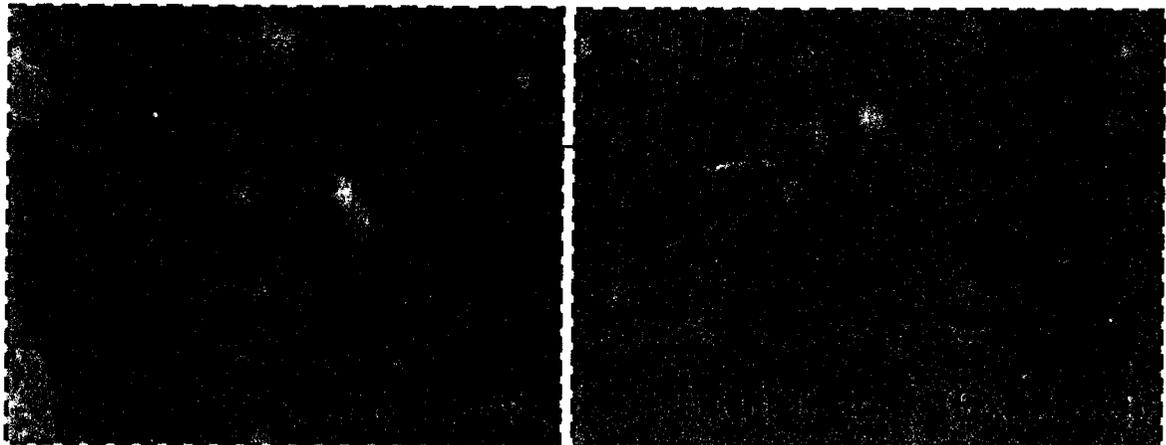
Pixel Detector



Microstrip Detector

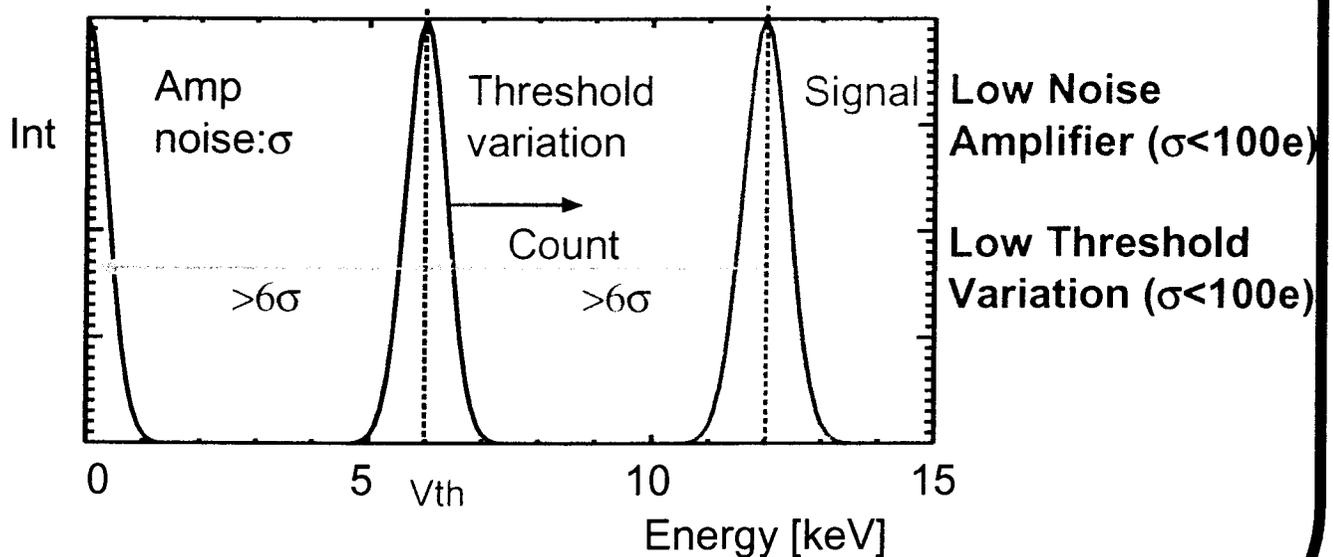
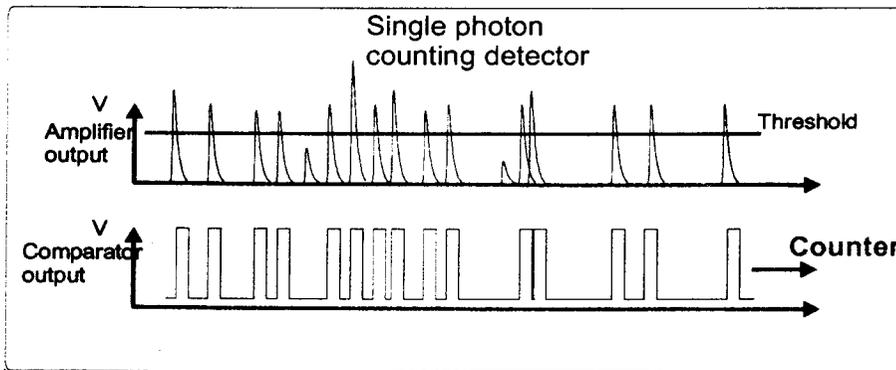
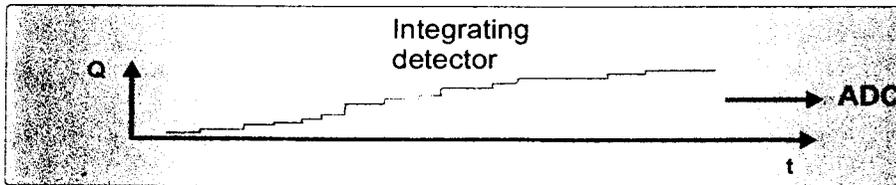
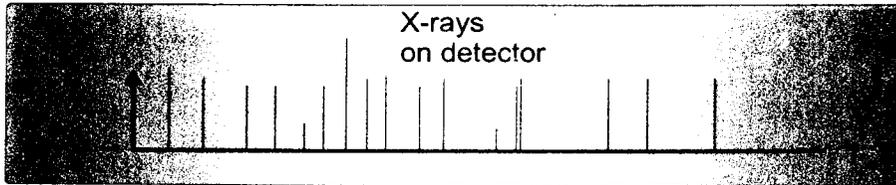


Electronics for each pixel (strip)



Earliest possible digitization !

Integrating Detector vs Single Photon Counting Detector

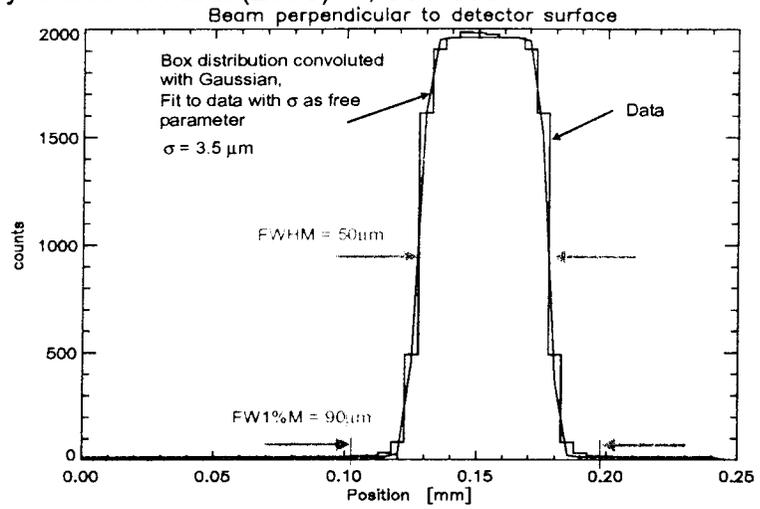


Very high dynamic range
 (But: Very dense mixed signal circuit in each pixel and on chip)

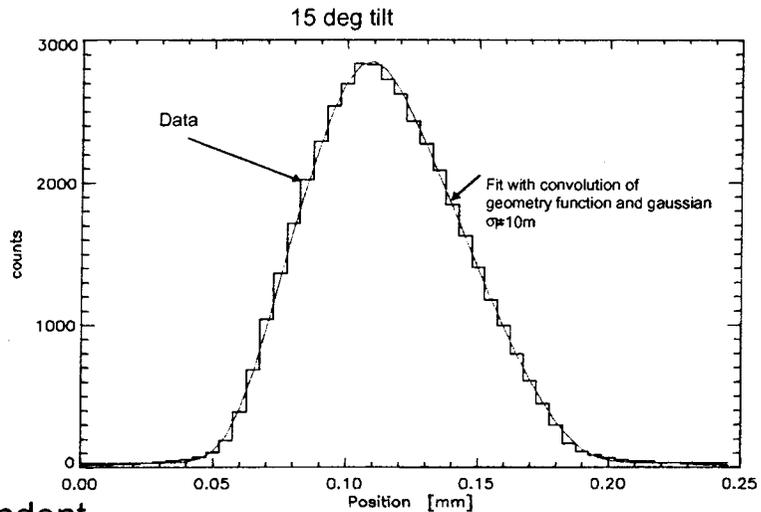
Single Photon Counting Detectors: Properties

Ch. Brönnimann et al, J. Synchrotron Rad. (2000). 7, 301-306

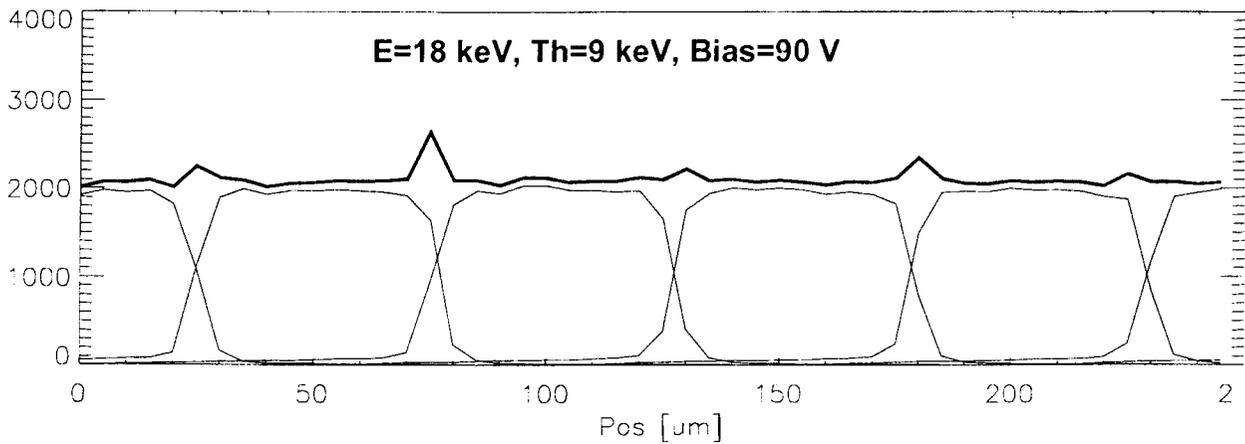
Excellent PSF:
Direct detection of X-rays



Parallax Effect:
Dependent on energy and angle of incidence of X-rays



Charge Sharing:
Energy and threshold dependent



The Pilatus Detector

Pixel Apparatus for the SLS



Pixel Detector for the Protein Crystallography Beamline 6S

PSI

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Ch. Bühler², U. Greuter², M. Näf¹, S. Streuli², R. Brun¹

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Pixel Detectors for Protein Crystallography

Spot size:

- Beam size and divergence
- Mosaicity of the crystal
- Distance sample-detector
- Point spread function of detector

Crystal rotation:

- 30-180 degrees for complete data set
- Currently: Discrete rotation, integration over certain rotation angle
- Fine ϕ -slicing with continuous sample rotation

Crystallized Protein

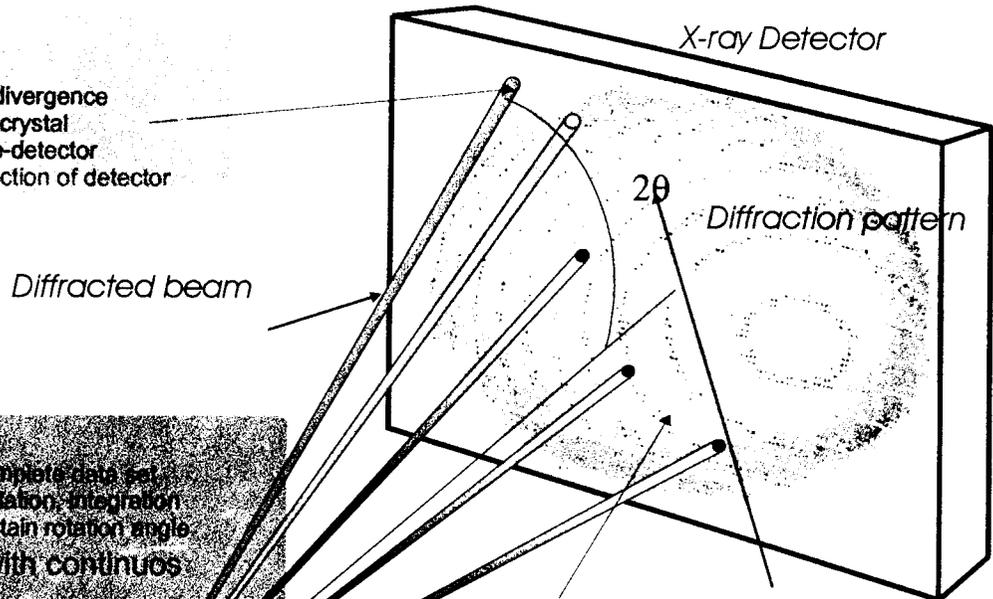
Beam

Beam:

Energy: 5-17.5 keV
Intensity: $>10^{12}/s$
Focal spot size: Adjustable to $>75 \times 30 \mu m^2$
Divergency: $<375 \times 70 \mu rad^2$ (FWHM)

Diffraction data

- reflect crystal symmetry group
- orientation of the crystal \rightarrow orientation matrix
- High dynamic range: $>10^4$ between strong and weak reflections
- Intensities need to be determined accurately (1%)
- Determination of amplitudes and phases leads to electron density maps



Resolution:

$$2d \cdot \sin(\theta) = \lambda$$

$$\text{For } d=\lambda=1A \quad 2\theta=60^\circ$$

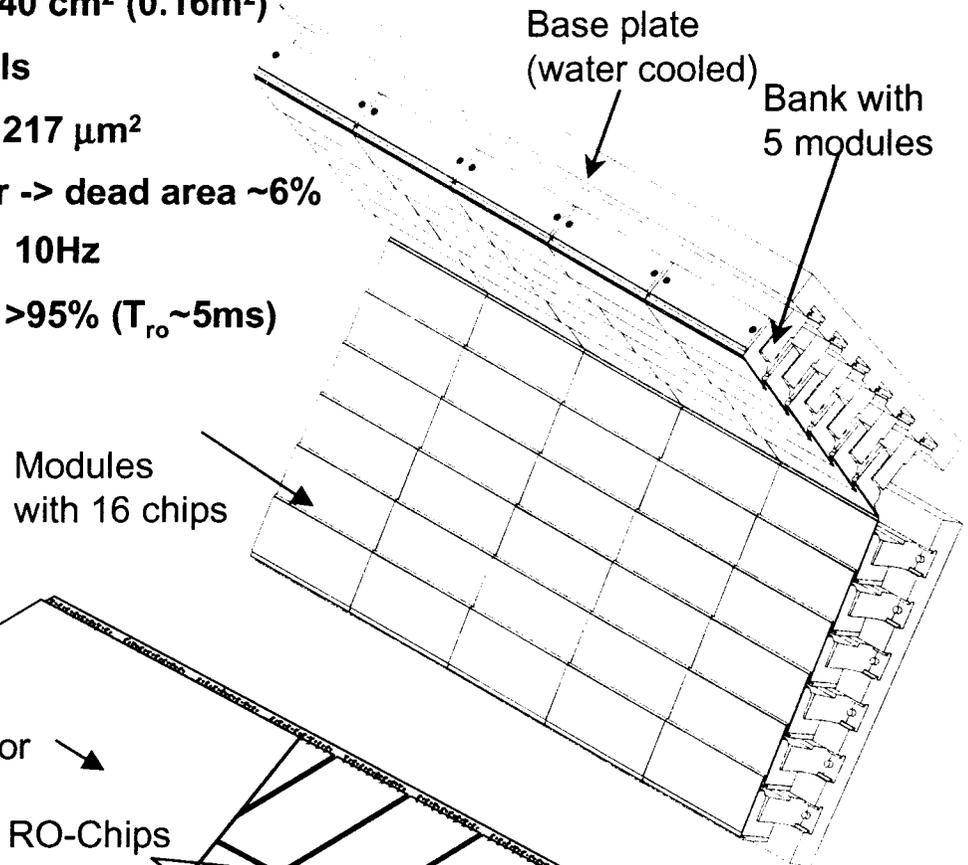
Main Detector Requirements:

- 1) Large area (40 x 40 cm) and/or large number of pixels to detect a high number of reflection orders (>500)
- 2) Accurate determination of integrated intensities (1%) and wide dynamic range (>16 bit), single photon counting detector
- 3) Fast readout ($\ll 0.1s$)

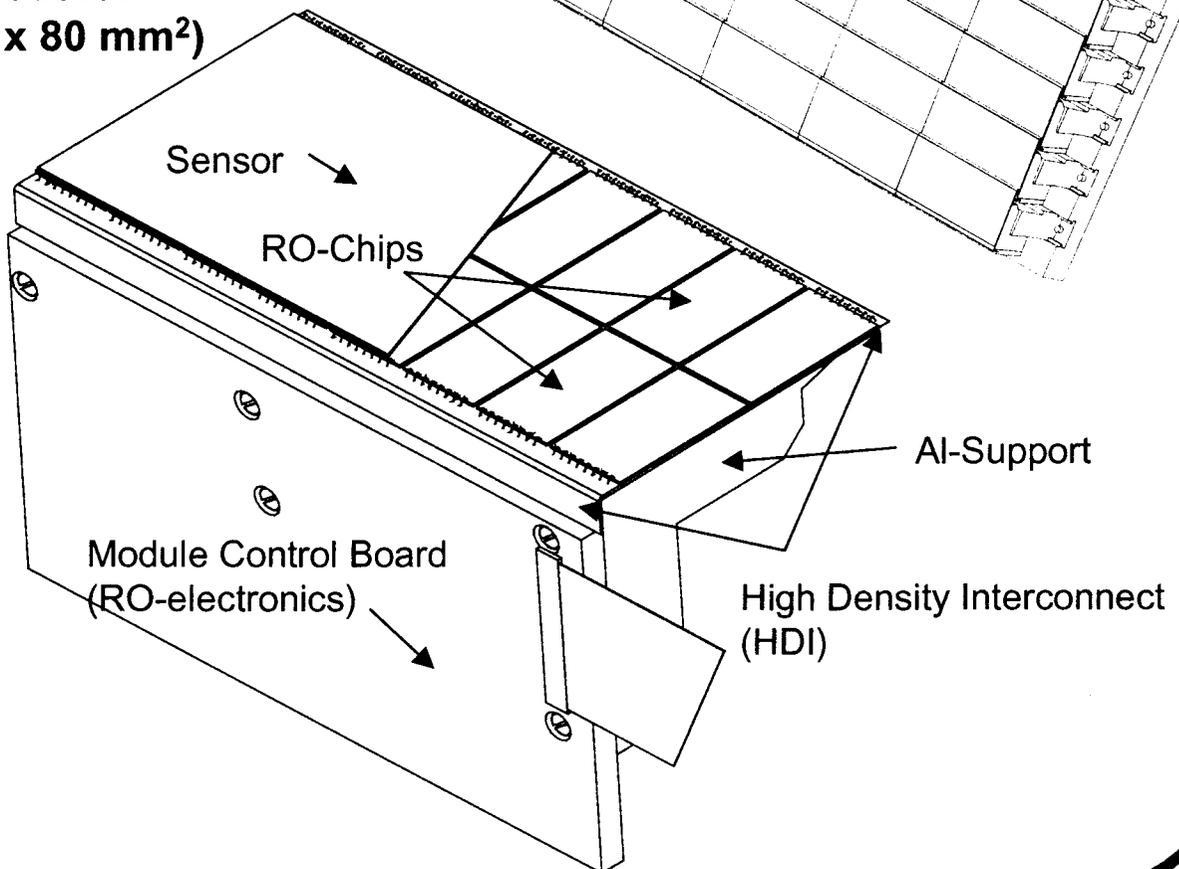
PILATUS Detector

- Final size: 40 x 40 cm² (0.16m²)
- 2000 x 2000 pixels
- Pixel size: 217 x 217 μm²
- Modular detector -> dead area ~6%
- High frame rate: 10Hz
- High duty cycle: >95% (T_{ro}~5ms)

Full Detector:

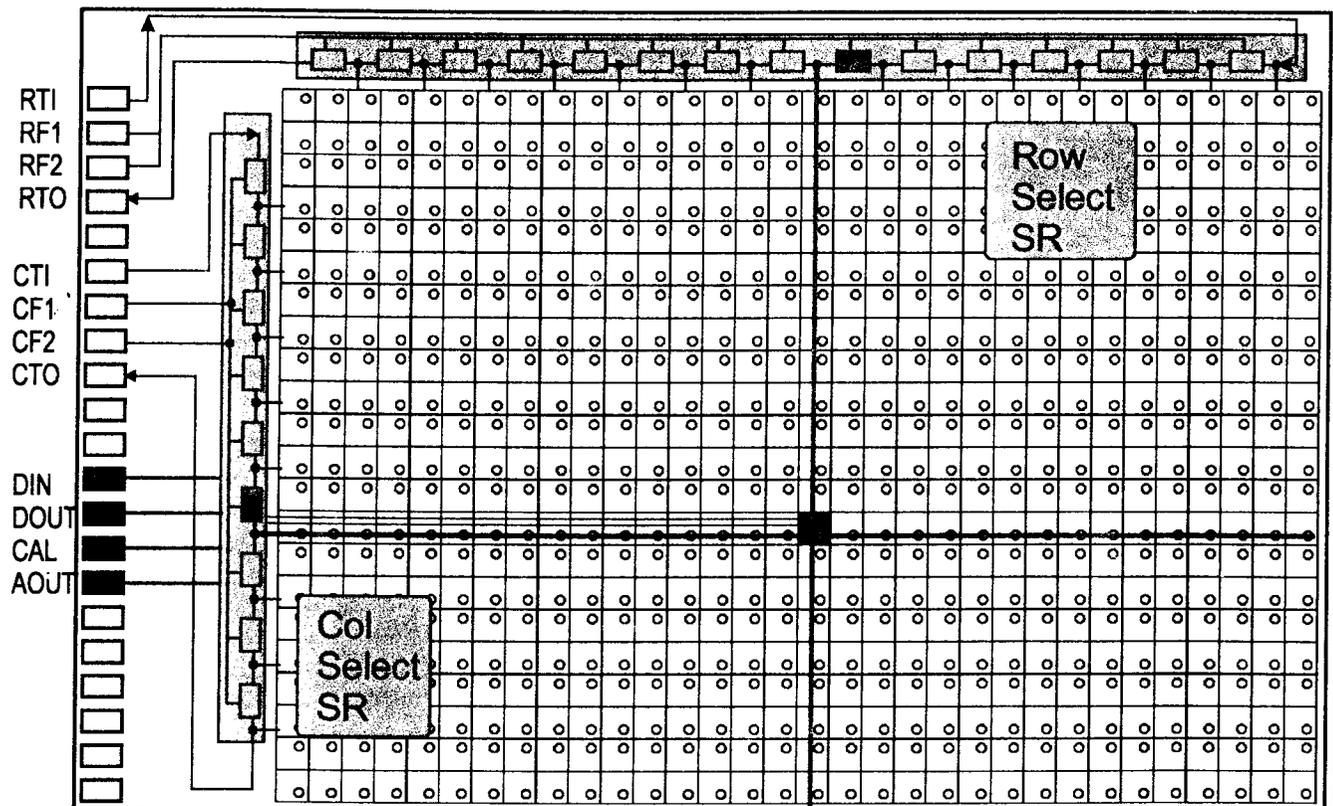


1 Module: (35 x 80 mm²)



PILATUS Chip: Specifications

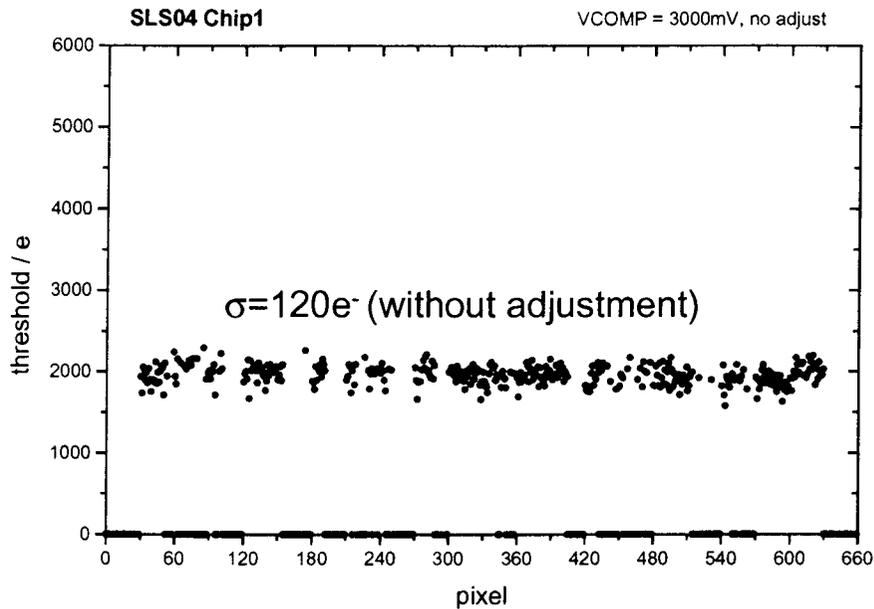
- Radiation tolerant DMILL technology
- Low noise analog block (ENC tot < 100 e-)
- Shaping time $t_{sh} = 100 \text{ ns} \rightarrow 1 \text{ MHz}$
- Individual threshold adjustment
- Low overall threshold variation ($\sigma < 100e^-$)
- 15 bit pseudo random counter
- Large size 44 x 78 pixels ($20 \times 10 \text{ mm}^2$)
- Each pixel is XY-addressable
- Read-out time: 5ms (at 10 MHz)



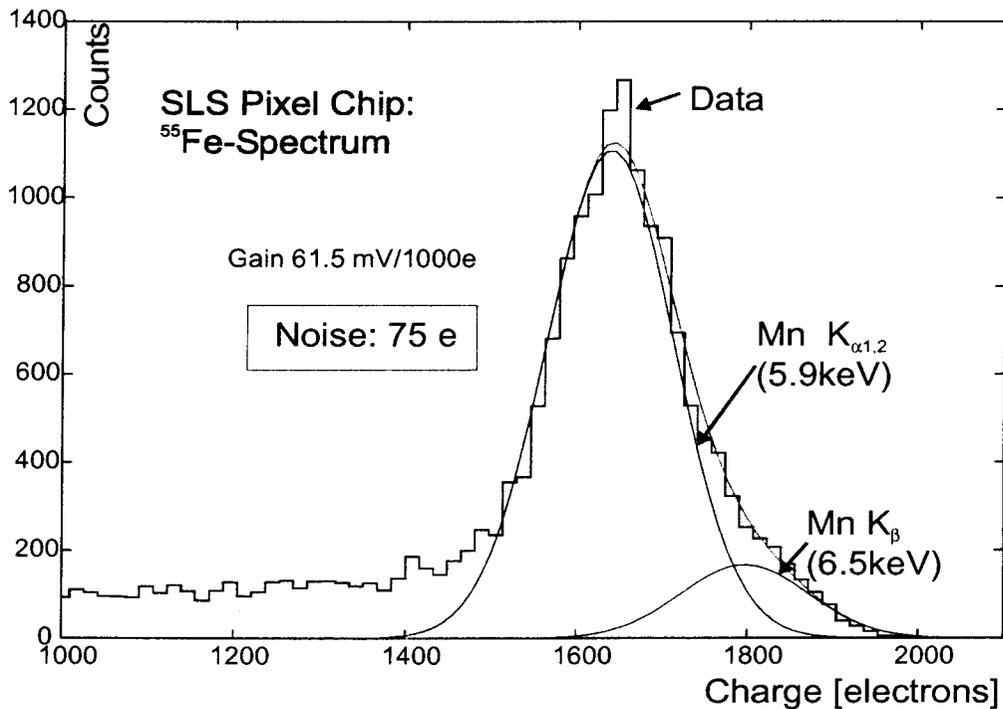
Submitted in Nov 2000

Results from SLS04 prototype readout chip (22 x 30 pixels)

Threshold values from scan of 660 pixels



^{55}Fe spectrum measured at the analog output of one pixel:



Read-out Electronics

Read-out clock:

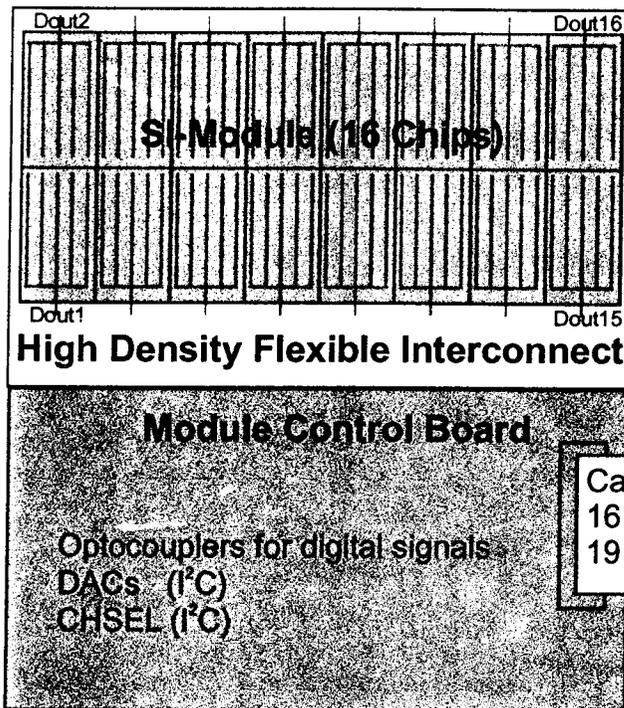
$$F_{RO} = 10 \text{ MHz}$$

Serial read-out of the 15 bits on each chip (3432 pixel)

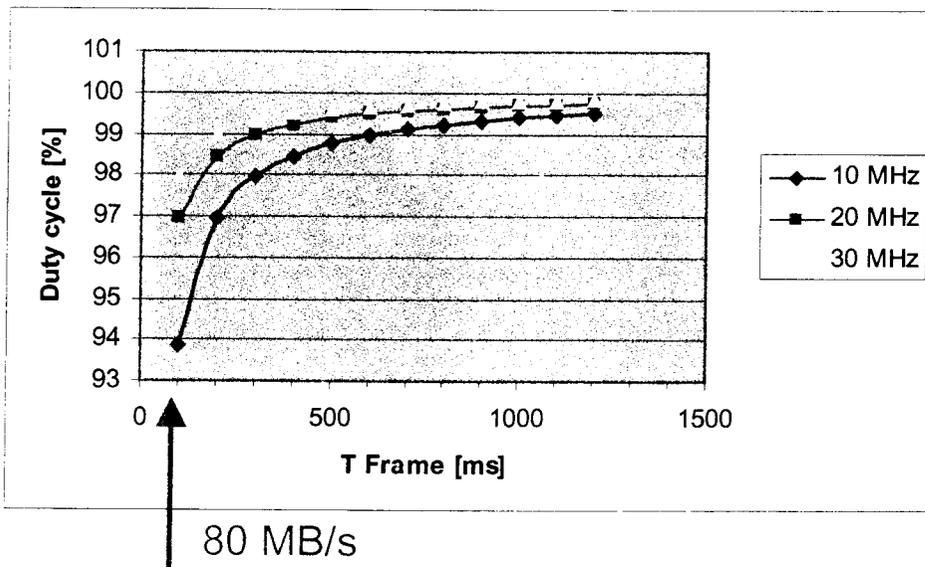
Parallel readout of 16 chips

Total read-out time/module:

$$T_{RO} = 5 \text{ ms}$$



$$\text{Duty Cycle [in \%]} = (T_{Fr} - T_{RO}) / T_{Fr}$$



The SLS Mythen Detector Microstrip System for Time-Resolved Experiments



**Microstrip Detector for the Powder Diffraction Station of the
Material Science Beamline 4s**

B. Schmitt¹, Ch. Brönnimann¹, E. Eikenberry¹, R. Baur² and R. Horisberger²

¹ *Swiss Light Source, Paul Scherrer Institut, CH-5232 Villigen-PSI*

² *CMS-Project, Paul Scherrer Institut, CH-5232 Villigen-PSI*

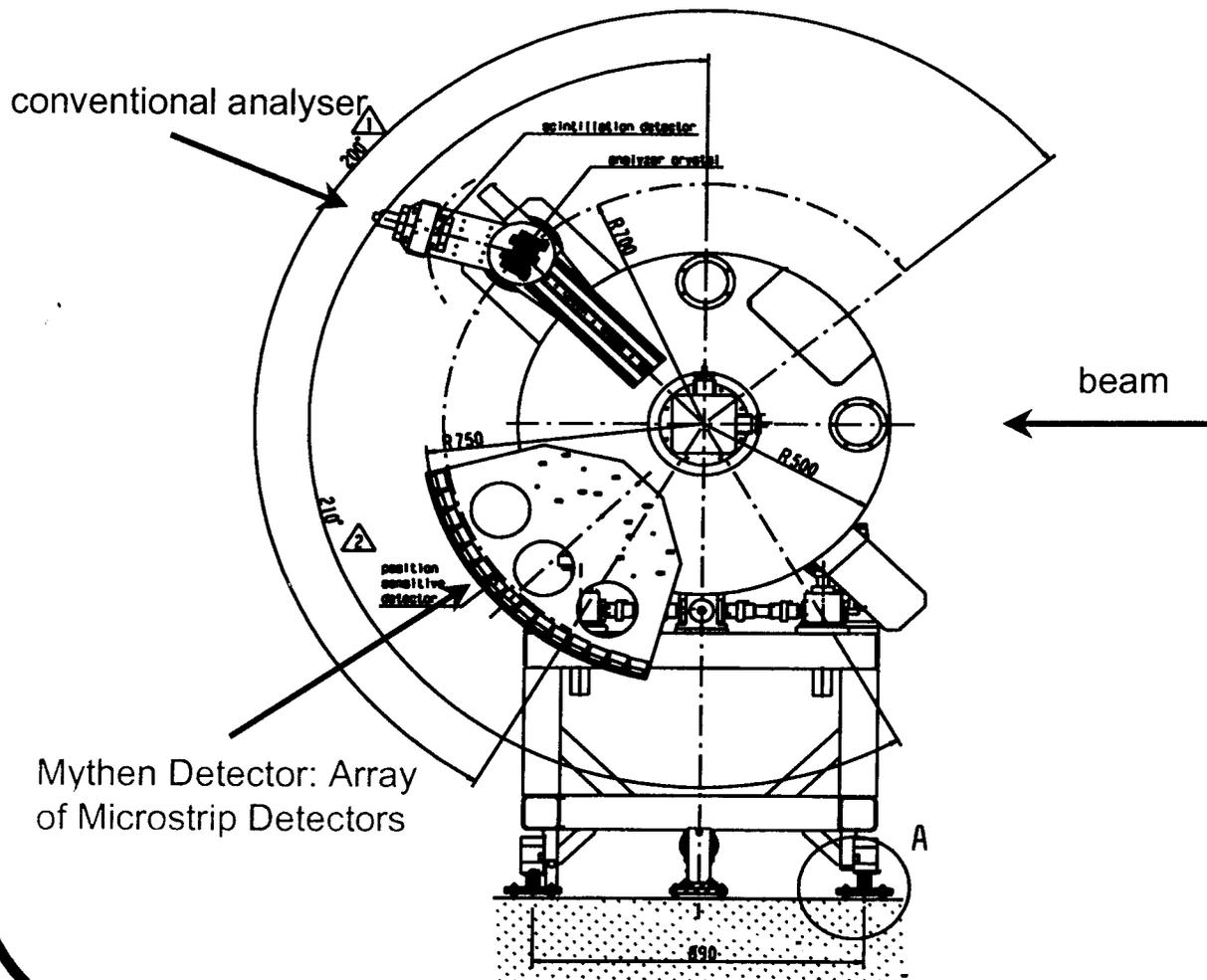
Powder Diffraction Station of the SLS Material Science Beamline 4S

Mythen: Array of microstrip detectors

Angular coverage: 60°
No of channels: 15000
Angular resolution : 0.004°
Read-out time: $244 \mu\text{s}$

→ time resolved powder diffraction

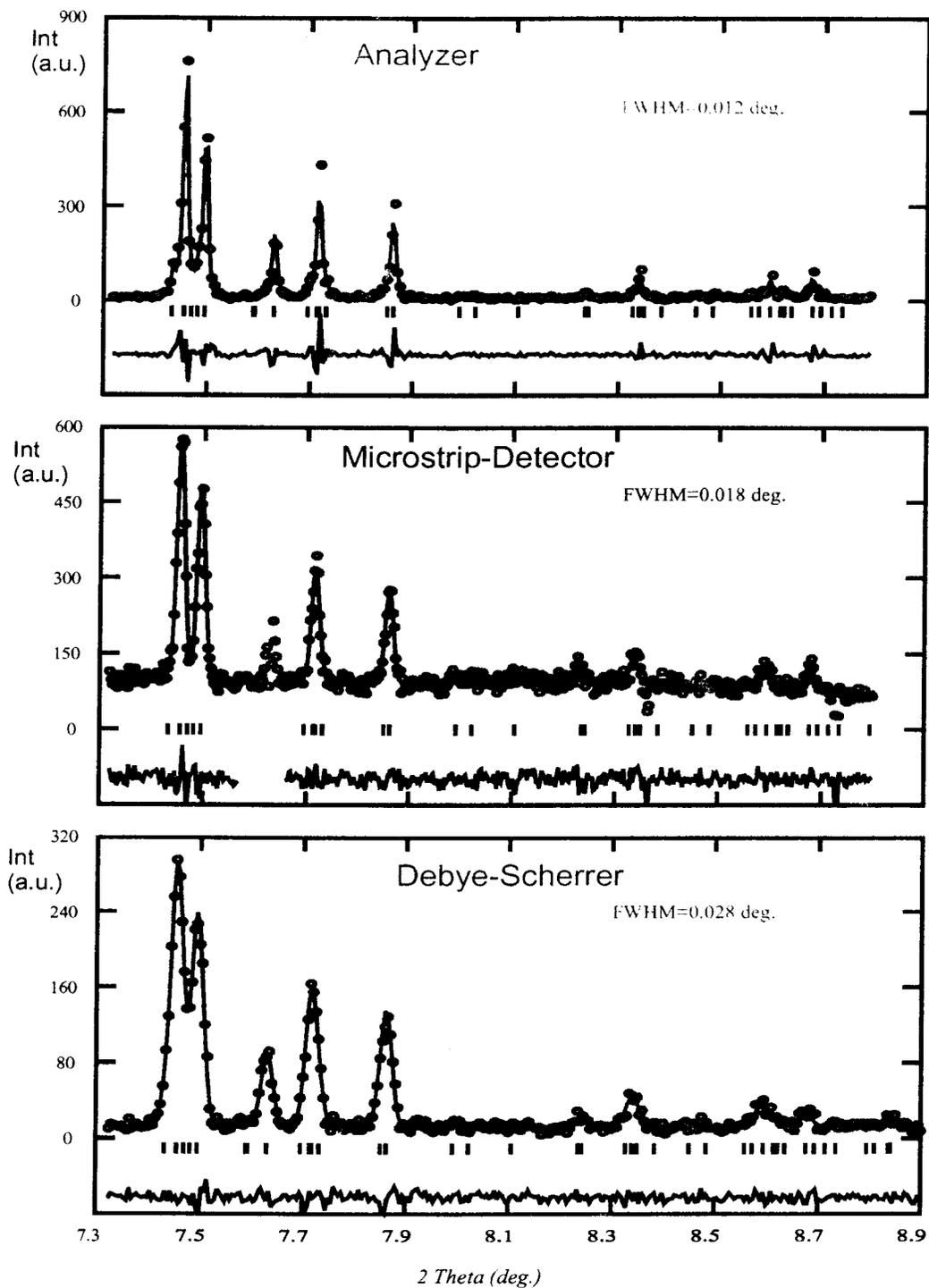
Experimental Set-up



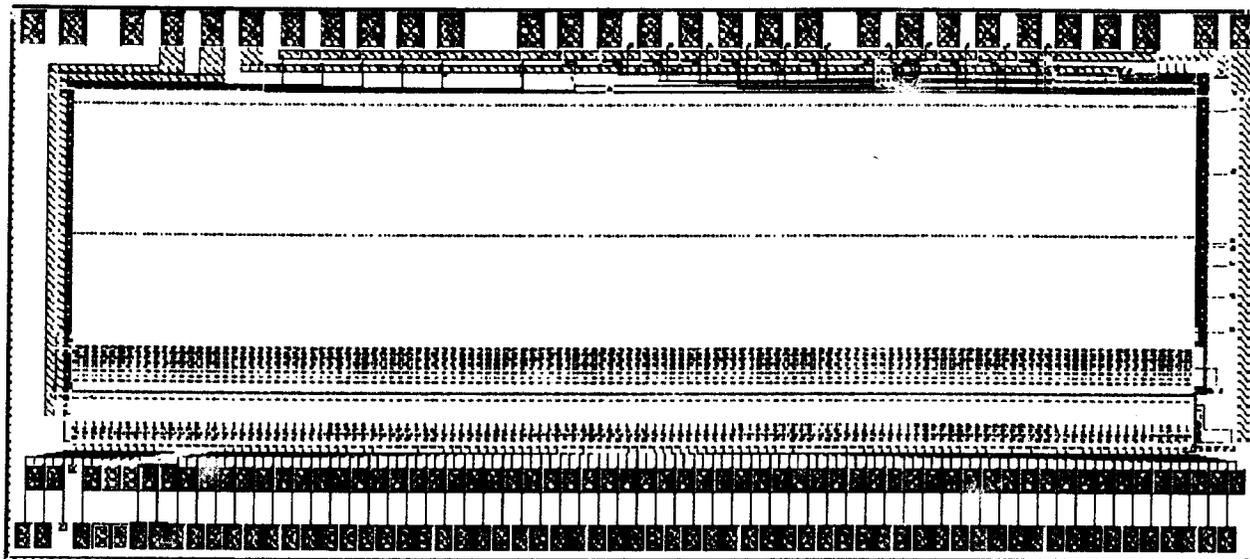
Comparison of analyzer and microstrip data

(F.Fauth et al, Nucl. Instr. Meth. A (2000), 439, no.1, p.138-46.

ZSM-5



The Mythen Readout Chip



Chip features:

Designed in 0.8 μ m DMILL process

128 channels, 50 μ m pitch

18 bit counter per pixel

Count rate 1MHz

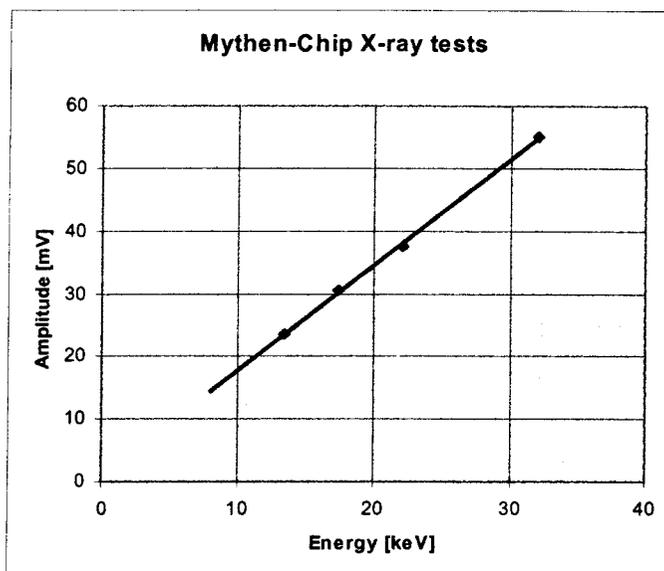
Readout time: 244 μ s

Threshold correction in each pixel

Low noise: 150 electrons

Single strip counting (ssc)

Fast Gate: 10ns



Pixel and Microstrip Detectors for Synchrotron Radiation Applications: Digital Systems

Summary and Conclusions

- Technologies of microstrip and pixel detectors so far driven by high rate HEP Experiments.
- 80% of the development time and costs for new detectors are put into ASIC-design and readout electronics.
-> need of good ASIC design teams
- Pixel detectors have a brilliant future. However, the needed efforts are sometimes underestimated...
- Microstrip detectors (although “old fashioned”) are believed to have a impact on synchrotron radiation applications. They are relatively easy and cheap to fabricate.